

Invers Metallographic Microscope

MEF 4a

Principle

Vertical or side lighting of the opaque sample, image generation via reflected light.

Manufacturer	Reichert Leica
Light Source	Halogen lamp
Magnification Range	10 - 1000x
Lenses	1x, 5x, 10x, 20x, 50x, 100x
Additional Optical Magnification	0.88, 1.0, 1.1, 1.5
Contrast Techniques	Brightfield Darkfield Polarization DIC (Nomarski-contrast)
Camera	CCD, 2/3-inch chip, 5 megapixel
Equipment	Image data base Image analysis software Panoramic image